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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.	
10/826,259	04/19/2004	Syotaro Ono	251907US-2S DIV	9423	
22850	7590 10/14/2005	EXAMINER			
OBLON, SPIVAK, MCCLELLAND, MAIER & NEUSTADT, P.C. 1940 DUKE STREET			PHAM, LONG		
			ART UNIT	PAPER NUMBER	
ALEXANDRIA, VA 22314				TATER NOMBER	
		2814			
			DATE MAILED: 10/14/2005		

Please find below and/or attached an Office communication concerning this application or proceeding.

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		Application No.	Applicant(s)			
Office Action Summary		10/826,259	ONO ET AL.			
		Examiner	Art Unit			
		Long Pham	2814			
Period fo	The MAILING DATE of this communication app or Reply	ears on the cover sheet with the	correspondence address			
WHIC - Exte after - If NC - Failu Any	ORTENED STATUTORY PERIOD FOR REPLY CHEVER IS LONGER, FROM THE MAILING DANSIONS of time may be available under the provisions of 37 CFR 1.1 SIX (6) MONTHS from the mailing date of this communication. O period for reply is specified above, the maximum statutory period were to reply within the set or extended period for reply will, by statute reply received by the Office later than three months after the mailing ed patent term adjustment. See 37 CFR 1.704(b).	ATE OF THIS COMMUNICATIO 36(a). In no event, however, may a reply be ti will apply and will expire SIX (6) MONTHS from , cause the application to become ABANDONI	N. mely filed n the mailing date of this communication. ED (35 U.S.C. § 133).			
Status						
1)	Responsive to communication(s) filed on					
2a)⊠	This action is <b>FINAL</b> . 2b) This action is non-final.					
3)[	Since this application is in condition for allowar	nce except for formal matters, pr	osecution as to the merits is			
	closed in accordance with the practice under E	x parte Quayle, 1935 C.D. 11, 4	53 O.G. 213.			
Disposit	ion of Claims					
4)⊠	Claim(s) 31-35 is/are pending in the application	n.				
•	4a) Of the above claim(s) is/are withdrawn from consideration.					
5)⊠	Claim(s) 34 and 35 is/are allowed.	e				
6)⊠	Claim(s) 31 is/are rejected.		•			
7)🛛	Claim(s) 32 and 33 is/are objected to.					
8)□	·Claim(s) are subject to restriction and/o	r election requirement.				
Applicat	ion Papers					
9)[	The specification is objected to by the Examine	if.				
•	The drawing(s) filed on is/are: a) acc		Examiner.			
	Applicant may not request that any objection to the	drawing(s) be held in abeyance. Se	ee 37 CFR 1.85(a).			
	Replacement drawing sheet(s) including the correct	tion is required if the drawing(s) is ol	ojected to. See 37 CFR 1.121(d)			
11)	The oath or declaration is objected to by the Ex	caminer. Note the attached Office	e Action or form PTO-152.			
Priority (	under 35 U.S.C. § 119					
	Acknowledgment is made of a claim for foreign  All b) Some * c) None of:		a)-(d) or (f).			
	1. Certified copies of the priority document		Van Ala			
	2. Certified copies of the priority document					
	3. Copies of the certified copies of the prior application from the International Bureau	•	ed in this National Stage			
* 5	See the attached detailed Office action for a list	• • • • • • • • • • • • • • • • • • • •	ed.			
Attachmen	nt(s)	_				
	ce of References Cited (PTO-892)	4) Interview Summar Paper No(s)/Mail D				
3) Infor	ce of Draftsperson's Patent Drawing Review (PTO-948) mation Disclosure Statement(s) (PTO-1449 or PTO/SB/08) er No(s)/Mail Date		Patent Application (PTO-152)	-		

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#### **DETAILED ACTION**

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# Rejections and/or objections necessitated by the amendments \*Claim Rejections - 35 USC § 103\*\*

- 1. The text of those sections of Title 35, U.S. Code not included in this action can be found in a prior Office action.
- 2. Claim 31 is rejected under 35 U.S.C. 103(a) as being unpatentable over Baliga (US patent 5,637,898) in combination with Hshieh et al. (US patent 6,518,127).

With respect to claim 31, Baliga teaches a method of manufacturing a power MOSFET, comprising (see figs. 2A-2K and 3 and associated text):

epitaxially growing a drift layer 112 of a first conductivity type (n) on a first conductivity type semiconductor substrate 114 used as a drain layer, said drift layer being doped with impurities having a concentration distribution increasing up to or toward said substrate (see abstract);

forming a base layer 116 of a second conductivity type (p) on said drift layer;

forming a source region 118 of the first conductivity type (n) on said base layer;

forming a trench penetrating said source region and said base layer to reach at said drift layer; and

forming trenched gate structure including a gate insulating film 124 and a gate electrode 126, said gate insulating film having a thin portion facing said base layer and a thick portion facing said drift layer.

Baliga fails to teach that the base layer is formed by epitaxial growth.

However, the formation of semiconductor layers by epitixial growth is well-known in the art.

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Further with respect to claim 31, Baliga fails to teach that a bottom portion of the trenched gate structure reaches into the drain layer.

Hshieh et al. teach that a bottom portion of a trenched gate structure 118, 125 reaches into a drain layer 111 to reduce unwanted resistance. See fig. 3 and associated text of Detailed of Description of Hshieh et al.

It would have been obvious to one of <u>ordinary skill</u> in the art of making semiconductor devices to incorporate the teaching of Hshieh et al. into the method of Baliga to achieve the above benefit.

## Allowable Subject Matter

- 1. Claims 32 and 33 are objected to as being dependent upon a rejected base claim, but would be allowable if rewritten in independent form including all of the limitations of the base claim and any intervening claims.
- 2. Claims 34 and 35 are allowed.

### Conclusion

3. Applicant's amendment necessitated the new ground(s) of rejection presented in this Office action. Accordingly, **THIS ACTION IS MADE FINAL**. See MPEP § 706.07(a). Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will

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the statutory period for reply expire later than SIX MONTHS from the date of this final action.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Long Pham whose telephone number is 571-272-1714. The examiner can normally be reached on M-F, 7:30AM-3:00PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Wael Fahmy can be reached on 571-272-1705. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Long Pham

Primary Examiner

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